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EL 739386125 US

MEMC 99-0900/2632  
PATENT

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Art Unit 1765

Application of Robert H. Fuerhoff et al.

Serial No. 09/502,340

Filed February 10, 2000

Confirmation No. 5009

For METHOD AND APPARATUS FOR CONTROLLING DIAMETER OF A SILICON  
CRYSTAL IN A LOCKED SEED LIFT GROWTH PROCESS

Examiner M. Anderson

May 15, 2001

**RESPONSE TO RESTRICTION REQUIREMENT**

TO THE ASSISTANT COMMISSIONER FOR PATENTS,

SIR:

In response to the restriction requirement dated April 24, 2001, applicants elect claims 1-10 (Group I) for examination. Applicants therefore withdraw claims 11-18 (Group II) from consideration, without prejudice to their patentability, and expressly reserve the right to file a divisional application directed to these claims. Applicants respectfully request examination and allowance of the elected claims.

The Commissioner is hereby authorized to charge any fees that may be required during the entire pendency of this application to Deposit Account No. 19-1345.

Respectfully submitted,

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